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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/695,028	10/24/2000	Jason Michael Benz	BUR9-2000-0047-US1	3674
21254 7	7590 07/08/2002			
MCGINN &	•	EXAMINER		
8321 OLD CO SUITE 200	URTHOUSE ROAD	ALANKO, ANITA KAREN		
VIENNA, VA	22182-3817		A DATE DATE	2 - 2 - 2 - 2 - 2 - 2 - 2 - 2 - 2 - 2 -
			ART UNIT	PAPER NUMBER
			1765	\triangleright
			DATE MAILED: 07/08/2002	0

Please find below and/or attached an Office communication concerning this application or proceeding.

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· · ·			A	pplication No		Applicant(s)	<u> </u>
	_		0	9/695,028		BENZ, JASON M	IICHAEL
	Offic	Action Summary	E	kaminer		Art Unit	
			At	nita K Alanko		1746	
: ۔۔ Period for I		ING DATE of this comm	unication appear	s on the cove	r sheet with the c	orrespondence ad	dress
A SHOF THE MA - Extension after SIX - If the per - If NO per - Failure to - Any reply	RTENED AILING D ons of time n (6) MONTH riod for reply riod for reply o reply within y received b	STATUTORY PERIOD OATE OF THIS COMMU nay be available under the provision of the state of this control of the state of the	NICATION. ons of 37 CFR 1.136(a) mmunication. (30) days, a reply with statutory period will ap ply will, by statute, caus s after the mailing date	. In no event, how in the statutory mipply and will expire se the application	ever, may a reply be tim nimum of thirty (30) days SIX (6) MONTHS from o become ABANDONEI	nely filed s will be considered time the mailing date of this of (35 U.S.C. § 133).	
1)□ F	Responsi	ive to communication(s)	filed on				
2a) <u> </u>	This actio	on is FINAL .	2b)⊠ This a	ction is non-f	inal.		
		s application is in conditi					ne merits is
Disposition		accordance with the pra ms	actice under <i>Ex</i> ,	parte Quayle	, 1935 C.D. 11, 4	53 O.G. 213.	
4)⊠ C	laim(s)	<u>1-30</u> is/are pending in th	e application.				
4a) Of the	above claim(s) is	/are withdrawn f	rom conside	ation.		
5)□ C	laim(s) _	is/are allowed.		ć			
6)⊠ C	laim(s) <u>1</u>	/-30 is/are rejected.					
7)□ C	laim(s) _	is/are objected to.					
8)∏ Cl Application		are subject to rest	riction and/or ele	ection require	ement.		
9)∐ Th	e specifi	cation is objected to by	the Examiner.				
10)□ Th	e drawin	g(s) filed on is/ar	e: a)∐ accepted	or b)☐ objec	ted to by the Exar	niner.	
		may not request that any o		-	-		
11) 🗌 Th	e propos	sed drawing correction fi	led on is:	a) approv	ed b)⊡ disappro	ved by the Examir	ner.
١	f approve	ed, corrected drawings are	required in reply t	o this Office ad	tion.		
12) Th	e oath oi	r declaration is objected	to by the Exami	ner.			
Priority und	der 35 U	I.S.C. §§ 119 and 120					
13) 🗌 🛚 Ad	cknowled	dgment is made of a clai	im for foreign pri	onty under 3	5 U.S.C. § 119(a)-(d) or (f).	
a) <u></u>	All b)□] Some * c) ☐ None of	:				
1.	☐ Cert	tified copies of the priorit	ty documents ha	ave been rec	eived.		
2.	☐ Cert	tified copies of the priori	ty documents ha	ive been rec	eived in Application	on No	
		oies of the certified copie application from the Inte ached detailed Office act	rnational Bureau	u (PCT Rule	17.2(a)).		Stage
_		ment is made of a claim			•		I application).
a) [The tra	anslation of the foreign lagment is made of a claim	anguage provisi	onal applicat	ion has been rec	eived.	
اکر این ا (Attachment(s		J on the made of a sidill	or aomodio pi	andor c	5.5.5. 33 120	and of the fi	
1) Notice of Notice of	f Referenc f Draftsper	res Cited (PTO-892) rson's Patent Drawing Review sure Statement(s) (PTO-1449)		4) 5) 6)		(PTO-413) Paper No Patent Application (PT	
S. Patent and Trade TO-326 (Rev. 0			Office Action	Summary		Part o	of Paper No. 8

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Drawings

Figures 1A-3B should be designated by a legend such as --Prior Art-- because only that which is old is illustrated. See MPEP § 608.02(g). A proposed drawing correction or corrected drawings are required in reply to the Office action to avoid abandonment of the application. The objection to the drawings will not be held in abeyance.

The drawings are objected to because Fig.1A, 2a, 3a are missing reference numbers that are described in the specification. A proposed drawing correction or corrected drawings are required in reply to the Office action to avoid abandonment of the application. The objection to the drawings will not be held in abeyance.

Claim Rejections - 35 USC § 112

Claims 7, 18 and 29 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

In the next to the last line of claims 7, 18, 29, the term "a film" renders the claim unclear in scope. It appears that "a film" should cite - -the film--, or - -the primary film-- or - -the secondary film--.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

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(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claims 1, 12 and 23 are rejected under 35 U.S.C. 102(b) as being clearly anticipated by Nishioka (U.S. Patent No. 4,767,495).

Nishioka discloses a method (Fig. 3A-3C) of etching a substrate comprising:

- ➤ measuring a reflectance signal L_{RO} from a reflective material 3 deposited on said substrate 1, 2 as the substrate is being etched;
- > correlating the substrate etch rate to the reflectance signal from the reflective material (col.5, section "B");
- > and using the etch relation between the substrate and the reflective material to determine the etch target.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-30 are rejected under 35 U.S.C. 103(a) as being unpatentable over the combination of Nishioka (U.S. Patent No. 4,767,495) and Jackson et al (U.S. Patent No. 5,335,113).

Nishioka discloses a method (Fig. 3A-3C) of etching a substrate comprising:

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> measuring a reflectance signal L_{RO} from a reflective material 3 deposited on said substrate 1, 2 as the substrate is being etched;

- > correlating the substrate etch rate to the reflectance signal from the reflective material (col.5, section "B");
- > and using the etch relation between the substrate and the reflective material to determine the etch target.

The substrate of Nishioka discloses to etch silicon oxide, for which is it obvious to have quartz. However, Nishioka does not disclose the combination of chrome and quartz for the substrate and reflective material. Jackson teaches that the combination of etching quartz through a chrome mask is a well known structure and process (col.6, line 55-col.7, line 4). It would have been obvious to use chrome and quartz as the mask and substrate in the method of Nishioka because the method of Nishioka is applicable to several mask and etch structures, and Jackson teaches that the structure of chrome and quartz is a useful structure for masking and etching.

As to claim 5, it would have been obvious to use the modified method of Nishioka for a photomask because they are made of the same materials as used for photomasks.

As to claims 6 and 8, Jackson does not disclose to take steps to prevent the formation of native oxides, therefore the metal layer of Jackson inherently has a native, metal oxide formed on the metal layer, which also acts as an anti-reflective layer.

As to claim 7, Nishioka discloses that the mask layer being monitored is not the layer being etched, thus the output being monitored does not physically represent the film being etched.

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Conclusion

The prior art made of record and not relied upon is considered pertinent to applicant's

disclosure. The cited art shows methods of endpoint detection.

Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Anita K Alanko whose telephone number is 703-305-7708. The

examiner can normally be reached on Monday-Friday,8:30 am-1:30 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's

supervisor, Randy Gulakowski can be reached on 703-308-4333. The fax phone numbers for

the organization where this application or proceeding is assigned are 703-872-9057 for regular

communications and 703-872-9311 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding

should be directed to the receptionist whose telephone number is 703-308-0661.

Anita K Alanko

Primary Examiner

Spitak Stanles

Art Unit 1746

AKA

July 1, 2002